

**OLIFF & BERRIDGE, PLC**  
ATTORNEYS AT LAW

**Application Data Sheet**

**Applicant Information**

Applicant Authority type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Shigehiro
Family Name::	NISHINO
City of Residence::	Kyoto-shi
Country of Residence::	Japan

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Applicant Authority Type::	Inventor
Primary Citizenship Country::	Japan
Status::	Full Capacity
Given Name::	Kazutoshi
Family Name::	MURATA
City of Residence::	Tamano-shi
Country of Residence::	Japan

**Correspondence Information**

Correspondence Customer Number::	25944
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**Application Information**

Application Type::	National Phase
Subject Matter::	Utility
CD-ROM or CD-R::	None
Title::	LARGE-DIAMETER SiC WAFER AND MANUFACTURING METHOD THEREOF
Attorney Docket Number::	122261
Suggested Drawing Figure::	1
Total Drawing Sheets::	3
Small Entity::	No

## Representative Information

<b>Domestic Priority Information</b>			
Application::	Continuity Type::	Parent Application::	Parent Filing Date::
This Application is a	National Stage of	PCT/JP03/08312	06/30/03
<b>Foreign Priority Information</b>			
Country::	Application Number::	Filing Date::	Priority Claimed::
Japan	2002-202953	07/11/02	Yes
<b>Assignee Information</b>			
Assignee Name::		Mitsui Engineering & Shipbuilding Co., Ltd.	
Street of mailing address::		6-4, Tsukiji 5-chome, Chuo-ku	
City of mailing address::		Tokyo	
Country of mailing address::		Japan	
Postal or Zip Code of mailing address::		104-8439	